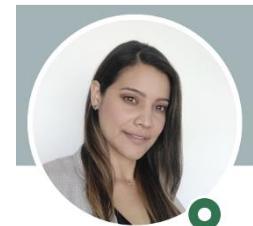


MICRO 423 : ADVANCED ADDITIVE MANUFACTURING TECHNOLOGIES

**3D printing using continuous wave light
(single photon absorption)**

Prof. Christophe Moser

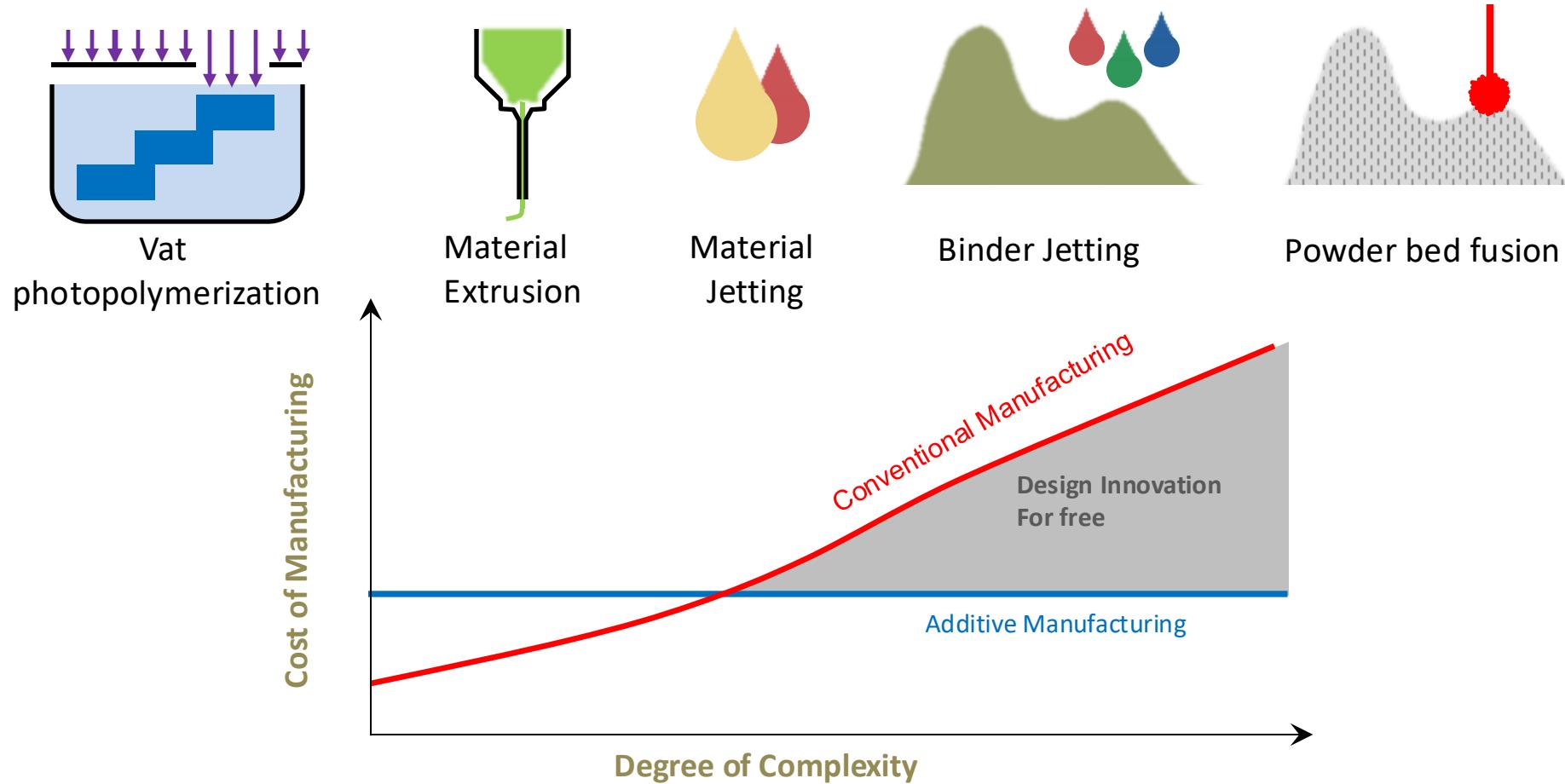
Maria Alvarez Castaño
maria.alvarezcastano@epfl.ch



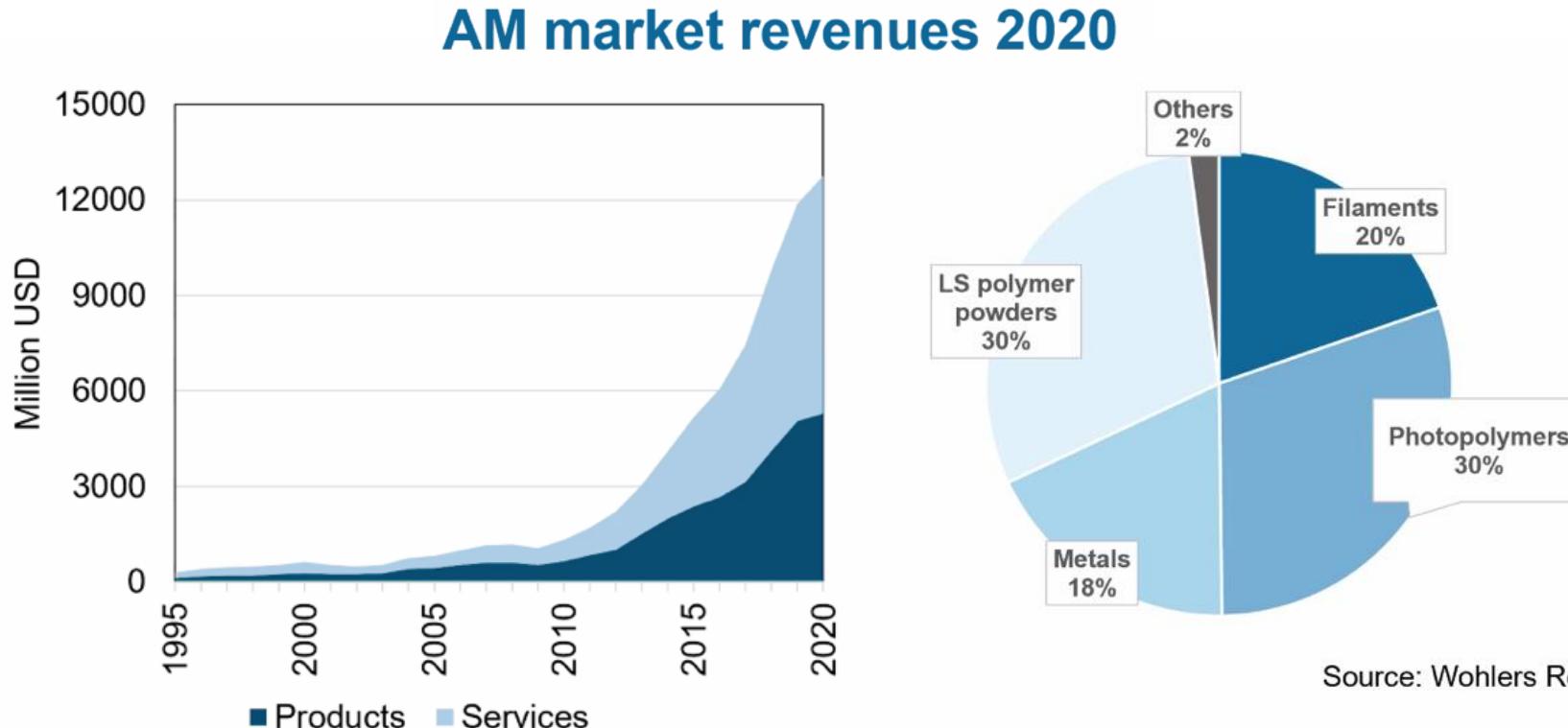
Modules of the 2025 course

Topics covered	No	Lecture/Date
VAT Photo polymerization (history) – DLP printer – light engine – part I	5	20.03.2025
DLP printer – chemical components in a photoresin – role of oxygen – CLIP method– part II	6	27.03.2025
Tomographic Volumetric Additive Manufacturing (TVAM)	7	03.04.2025
Two photon Polymerization : nanoscale printing	8	10.04.2025
Two photon Polymerization : applications	9	17.04.2025
EASTER BREAK		22.04.2025
Prof. Paul Dalton, University of Oregon: Met Electro Writing (nanoscale)	10	1.05.2025
Gari Arutinov, Holst Center for AM: Mass transfer of microcomponents	11	08.05.2025
Julian Schneider: Scrona	12	15.05.2025
Patrizia Richner: Sonova (hearing aids). //	13	22.05.2025
Design Competition		

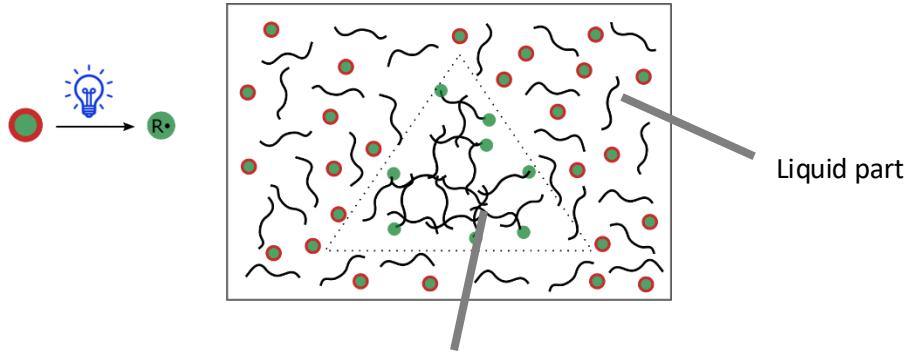
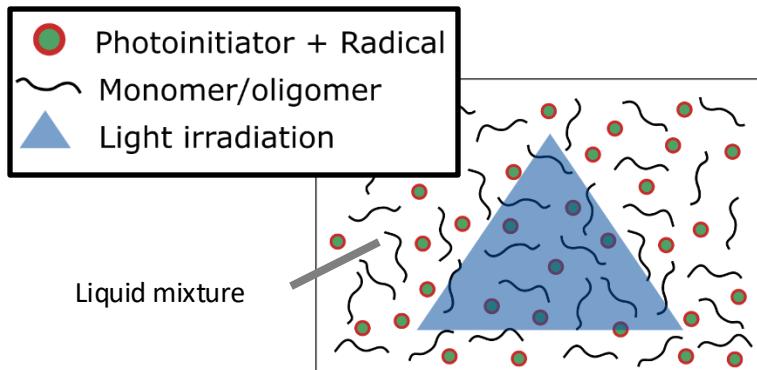
QUIZZ #2



Are polymers important in AM ?



Photopolymerization



Historical perspective

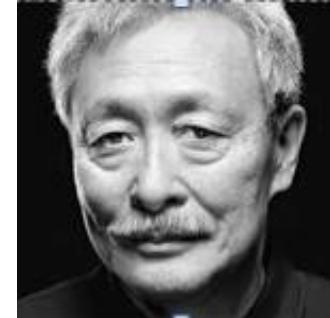
First use of single photon polymerization in 3D printing

Automatic method for fabricating a three-dimensional plastic model with photo-hardening polymer

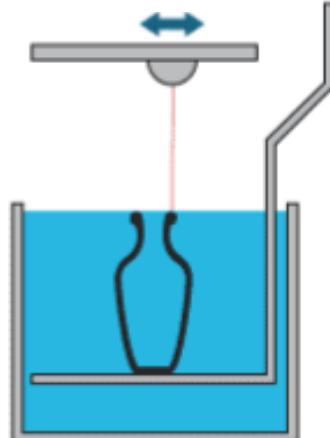
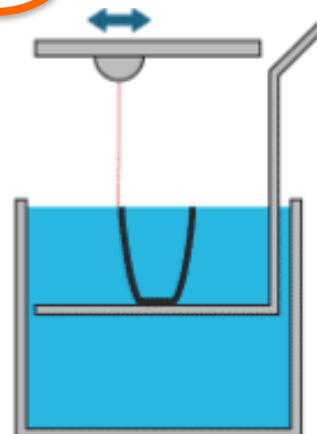
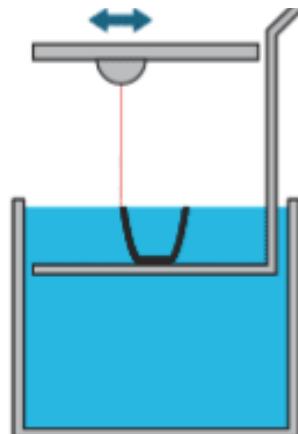
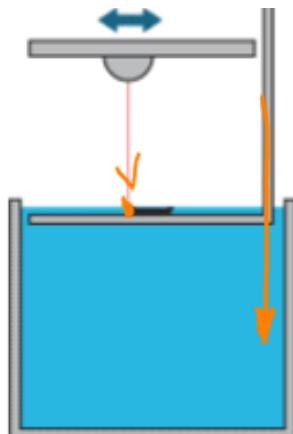
Hideo Kodama

Nagoya Municipal Industrial Research Institute, 3-24 Rokuban-cho, Atsuta-ku, Nagoya 456, Japan

(Received 10 February 1981; accepted for publication 2 August 1981)

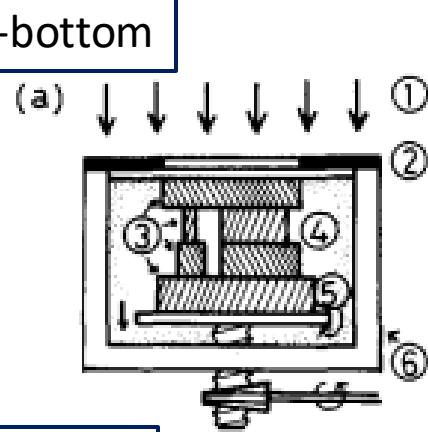


Review of Scientific Instruments,
Vol. 52, Issue 11, Nov. 1981

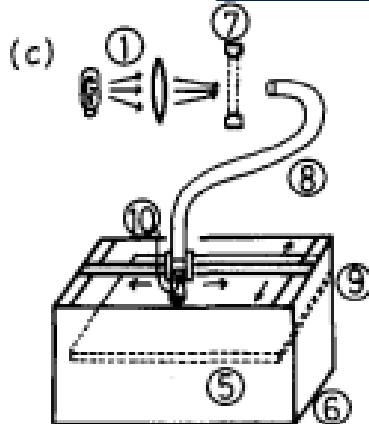


Historical perspective

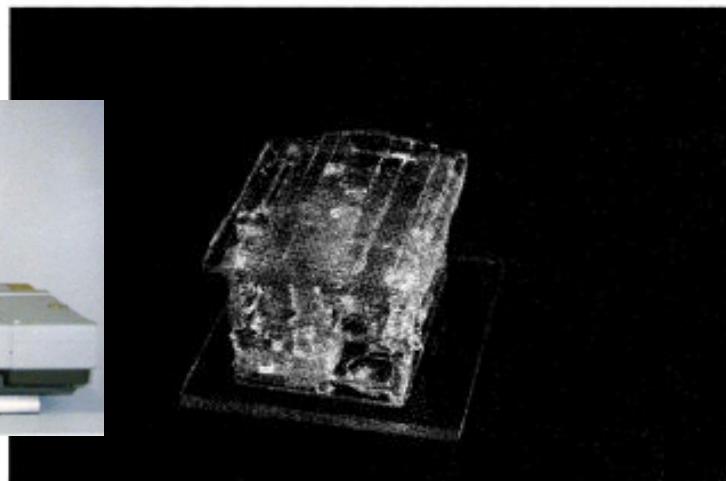
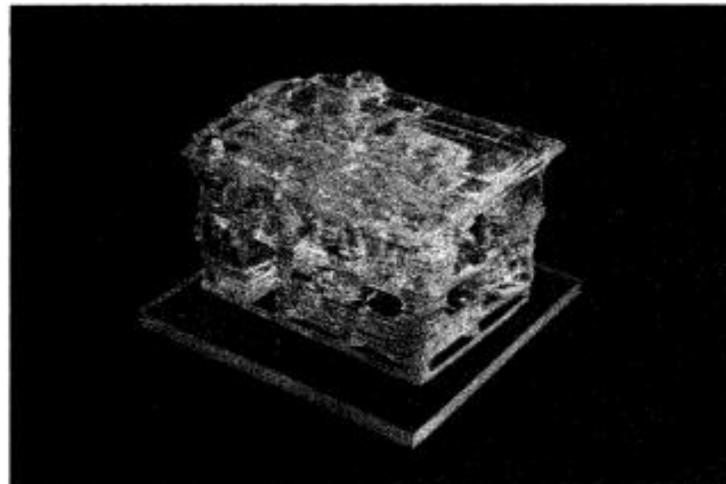
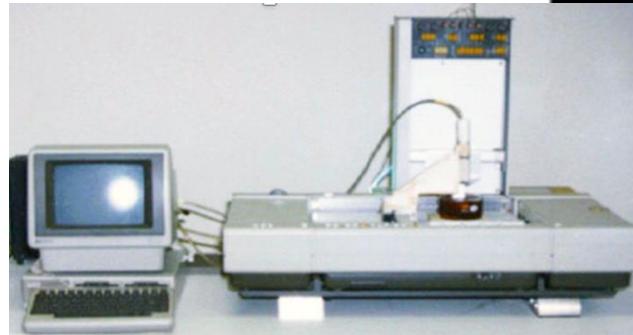
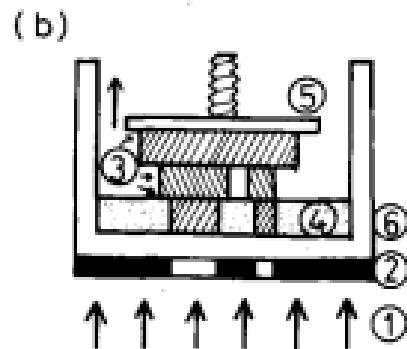
Top-bottom



Point by Point



Bottom-up



1980: First patent by Japanese Dr. Kodama for Rapid Prototyping : *“a vat of photopolymer material is exposed to a UV light that hardens the part and builds up the model in layers”*.

Not enough



... the full patent was not filed within the 1-year deadline !

1984: 3 French scientists at CNRS independently discover the same thing, file at patent application on July 16, 1984.

Alcatel – Cilas drop the application **“for lack of business perspective” !!**

1984: In the US, Chuck Hulls independently discovers the same thing, file a patent application on Aug. 8, 1984.

(22) Date de dépôt : 16 juillet 1984.

(30) Priorité :

(43) Date de la mise à disposition du public de la demande : BOPI « Brevets » n° 3 du 17 janvier 1986.

(60) Références à d'autres documents nationaux appartenants :

(71) Demandeur(s) : COMPAGNIE INDUSTRIELLE DES LASERS CILAS ALCATEL, société anonyme. — FR.

(54) Dispositif pour réaliser un modèle de pièce industrielle.

(72) Inventeur(s) : Jean-Claude André, Alain Le Mehauté et Olivier De Witte.

(73) Titulaire(s) :



3D SYSTEMS®

\$ 600 Million/year

United States Patent [19]

Hull

[11] Patent Number: 4,575,330

[45] Date of Patent: Mar. 11, 1986

[54] APPARATUS FOR PRODUCTION OF
THREE-DIMENSIONAL OBJECTS BY
STEREOLITHOGRAPHY

[75] Inventor: Charles W. Hull, Arcadia, Calif.

[73] Assignee: UVP, Inc., San Gabriel, Calif.

[21] Appl. No.: 638,905

[22] Filed: Aug. 8, 1984

4,252,514	2/1981	Gates	425/162
4,288,861	9/1981	Swainson et al.	365/127
4,292,015	9/1981	Hritz	425/162 X
4,329,135	5/1982	Beck	425/174
4,333,165	6/1982	Swainson et al.	365/127 X
4,374,077	2/1983	Kerfeld	264/22
4,466,080	8/1984	Swainson et al.	365/127 X
4,471,470	9/1984	Swainson et al.	365/127

Primary Examiner—J. Howard Flint, Jr.



BEYOND
3D PRINTING

Play (k) MARCH 2015 TED

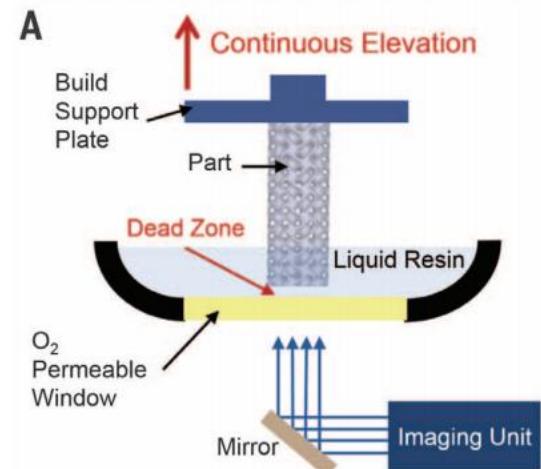
0:19 / 10:46

ADDITIVE MANUFACTURING

Continuous liquid interface production of 3D objects

2015
1200 citations

John R. Tumbleston,¹ David Shirvanyants,¹ Nikita Ermoshkin,¹ Rima Janusziewicz,² Ashley R. Johnson,³ David Kelly,¹ Kai Chen,¹ Robert Pischmidt,¹ Jason P. Rolland,¹ Alexander Ermoshkin,^{1,*} Edward T. Samulski,^{1,2,*} Joseph M. DeSimone^{1,2,4,*}



Carbon 3D

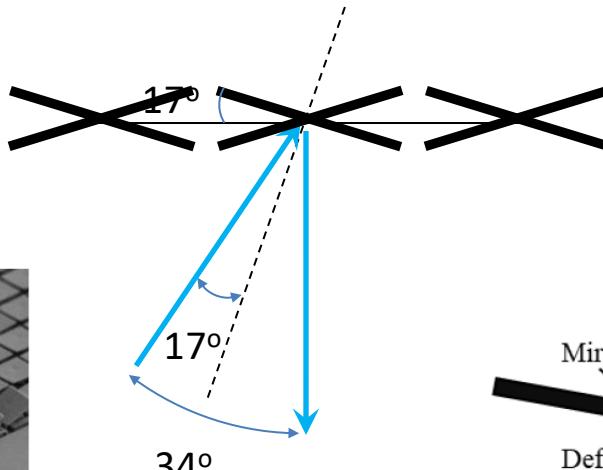
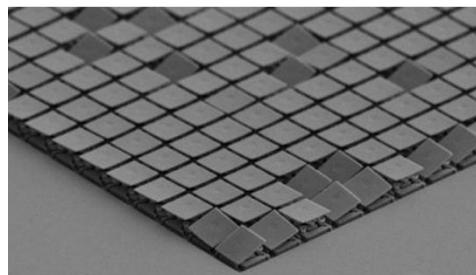


Founded 2013: Raised \$422 M.

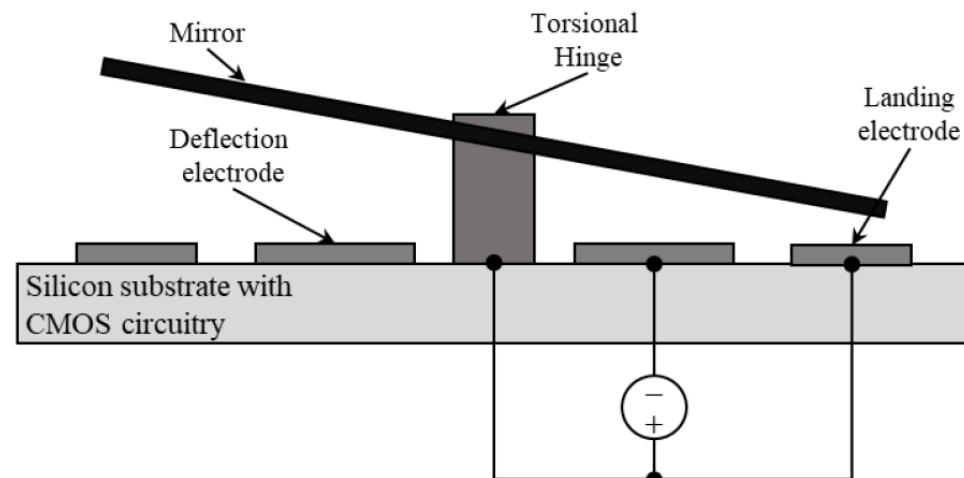
Advanced additive manufacturing technologies – week 5, 2025

- light engine for DLP printing
- Experiments with DLP
- Resin chemistry

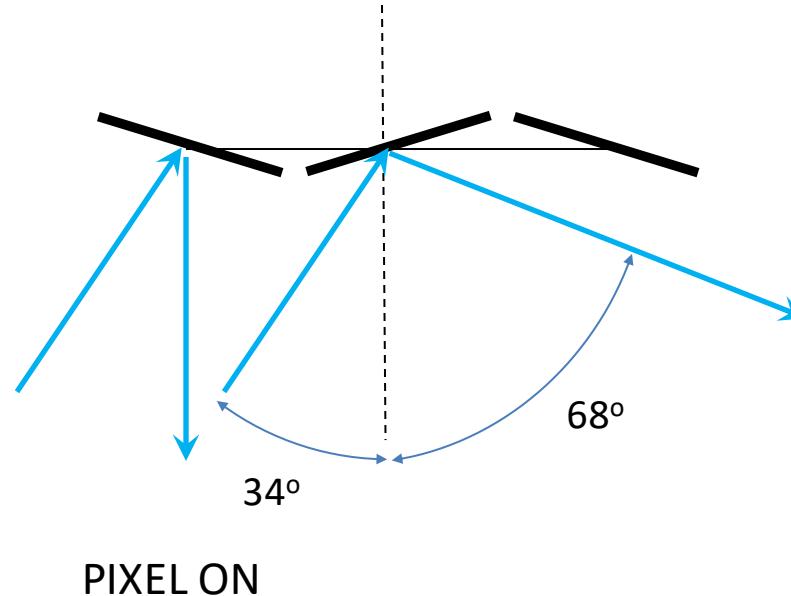
Digital MicroMirror Array (DLP™)



Pixel size.
5.4 x .5.4 μm
1920 x 1080 pixels



Digital MicroMirror Array (DLP™)



LOST LIGHT : PIXEL OFF

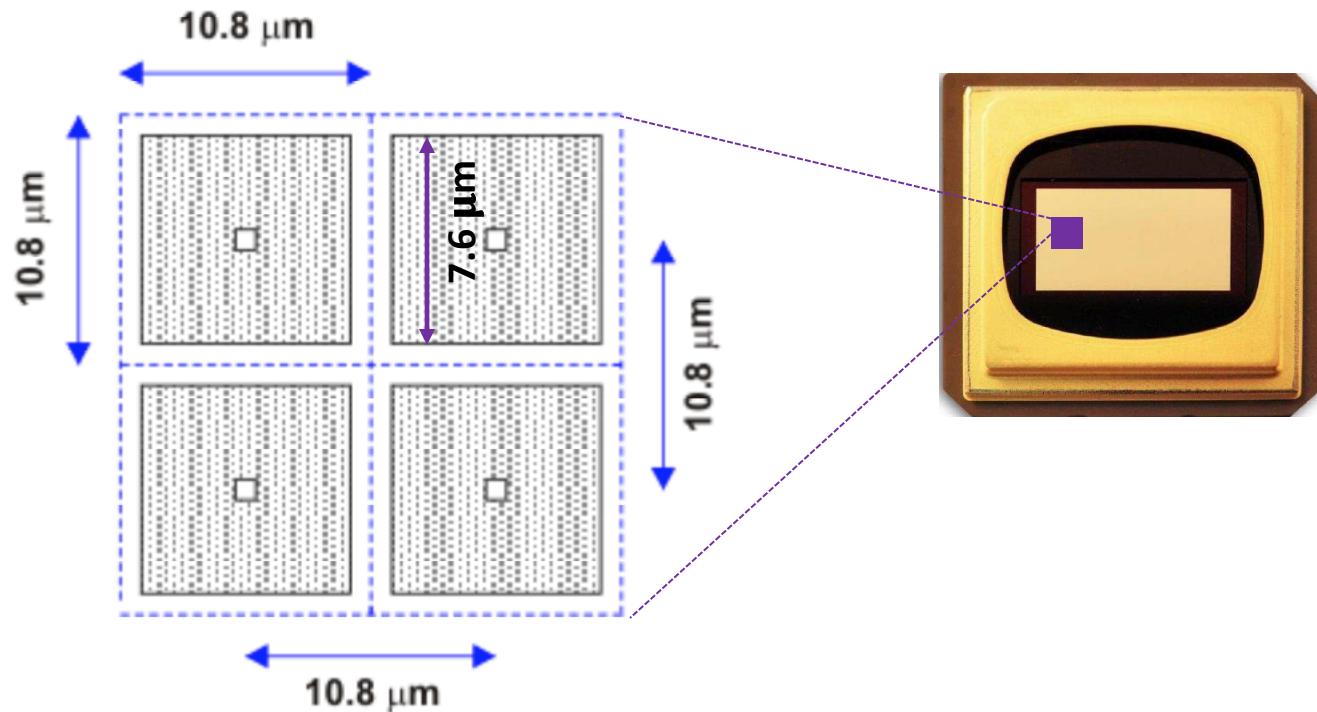
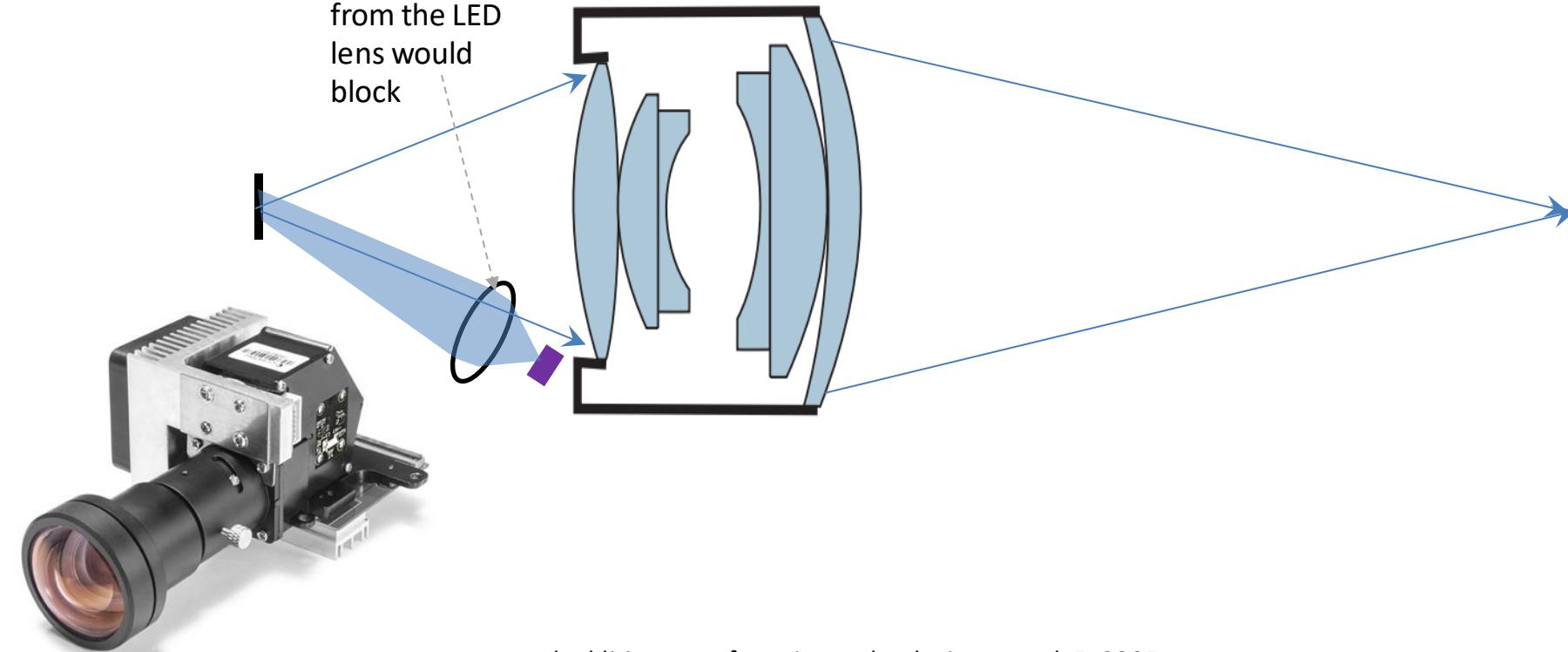
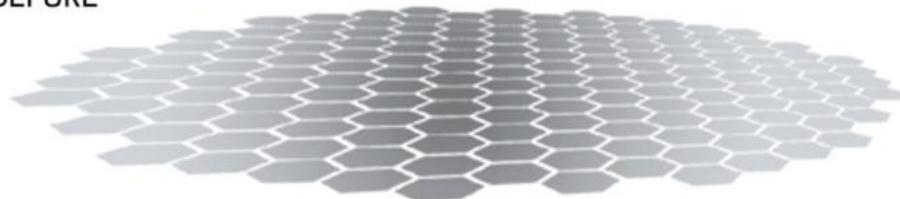


Figure 4. DLP5500 Micromirror Pitch

This
Angle is too
small. Light
from the LED
lens would
block



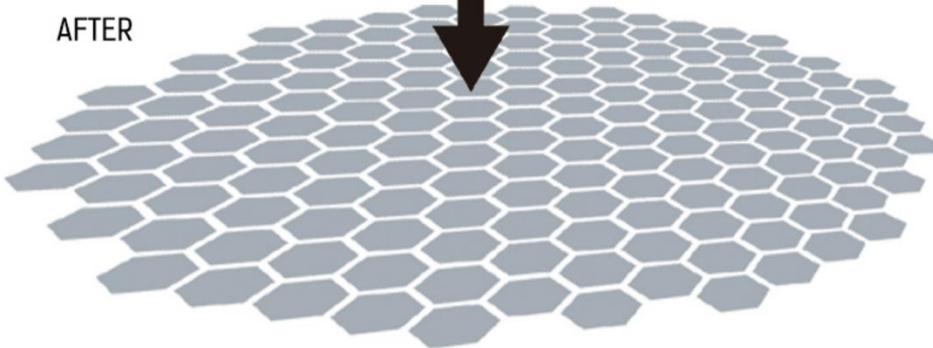
BEFORE



Light intensity uniformity
(pixel by pixel attenuation)



AFTER



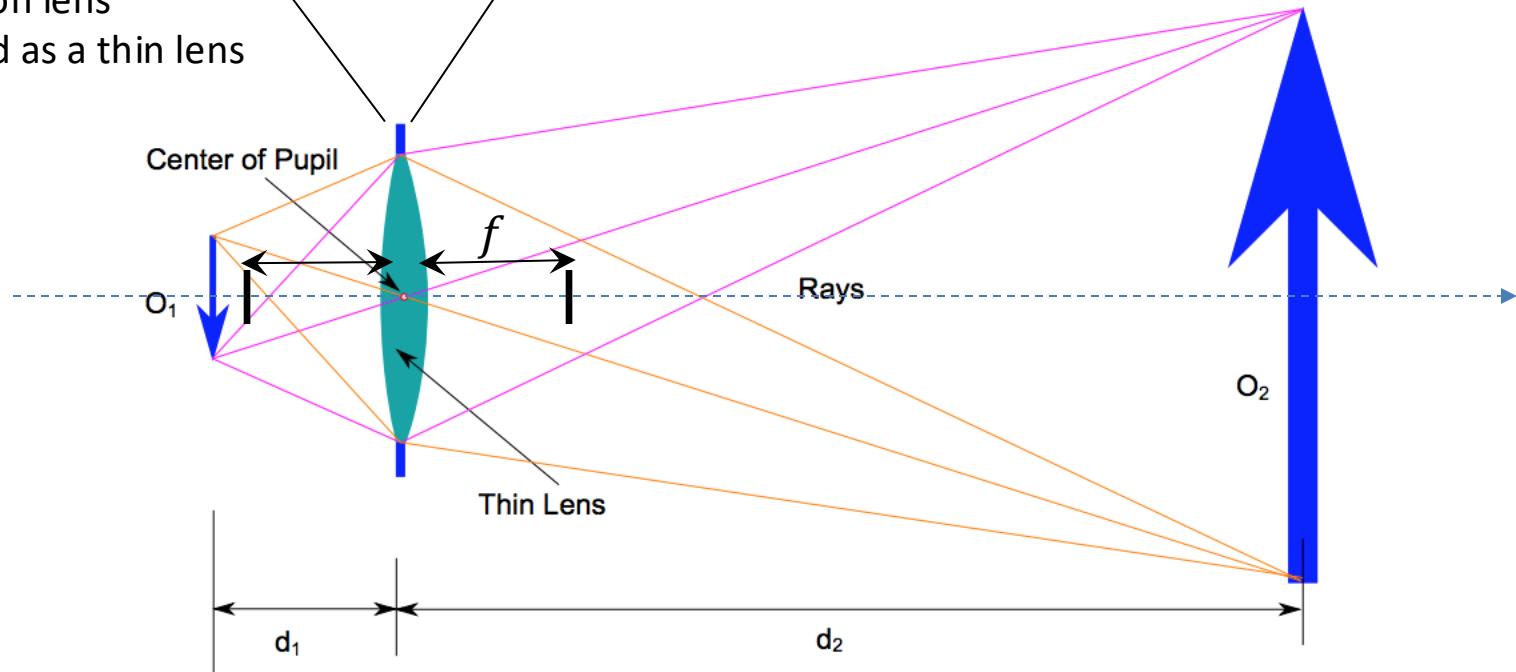
Build Volume: 4.72" x 2.66" x 5.91"

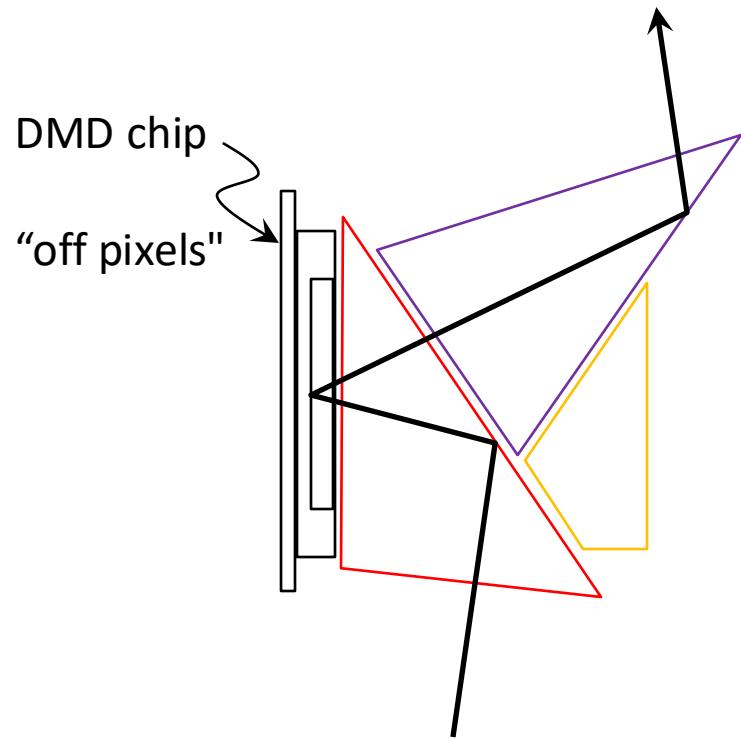
(120 x 67.5 x 150mm)
L x W x H

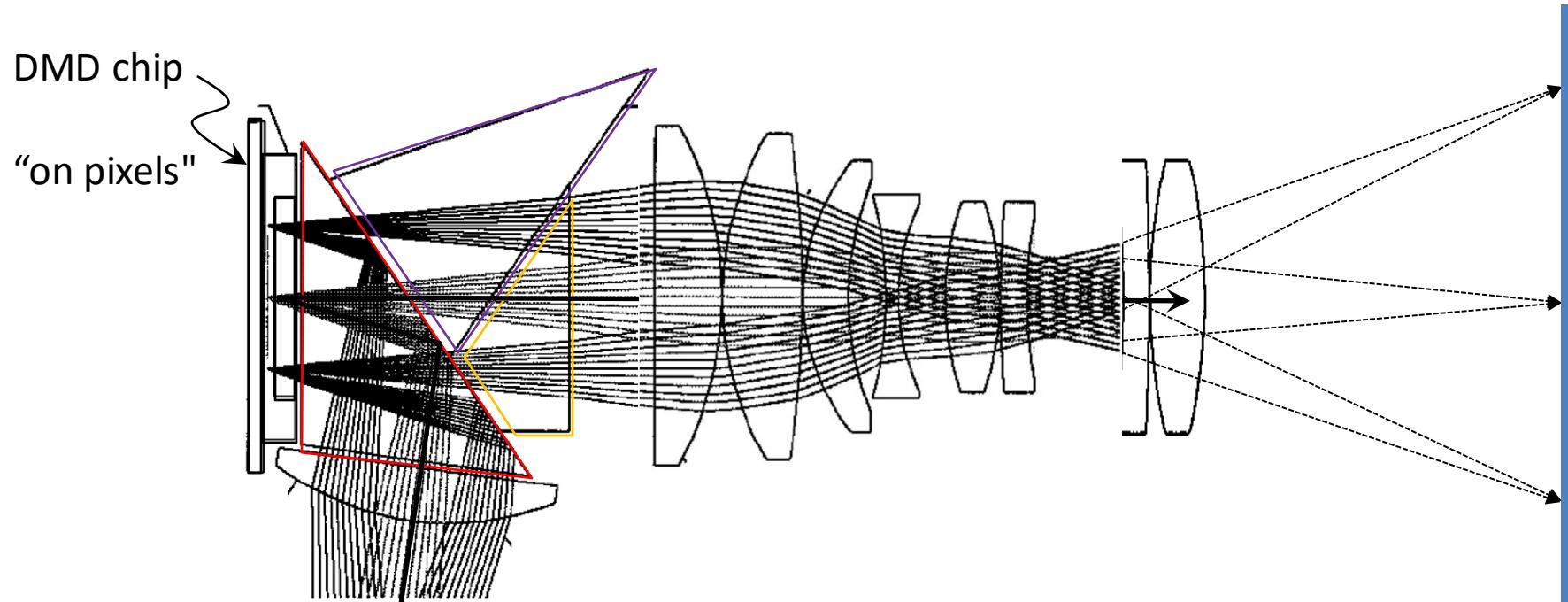
Pixel Size X, Y: 0.0025" (62.5µm)



Complex
Projection lens
Modeled as a thin lens



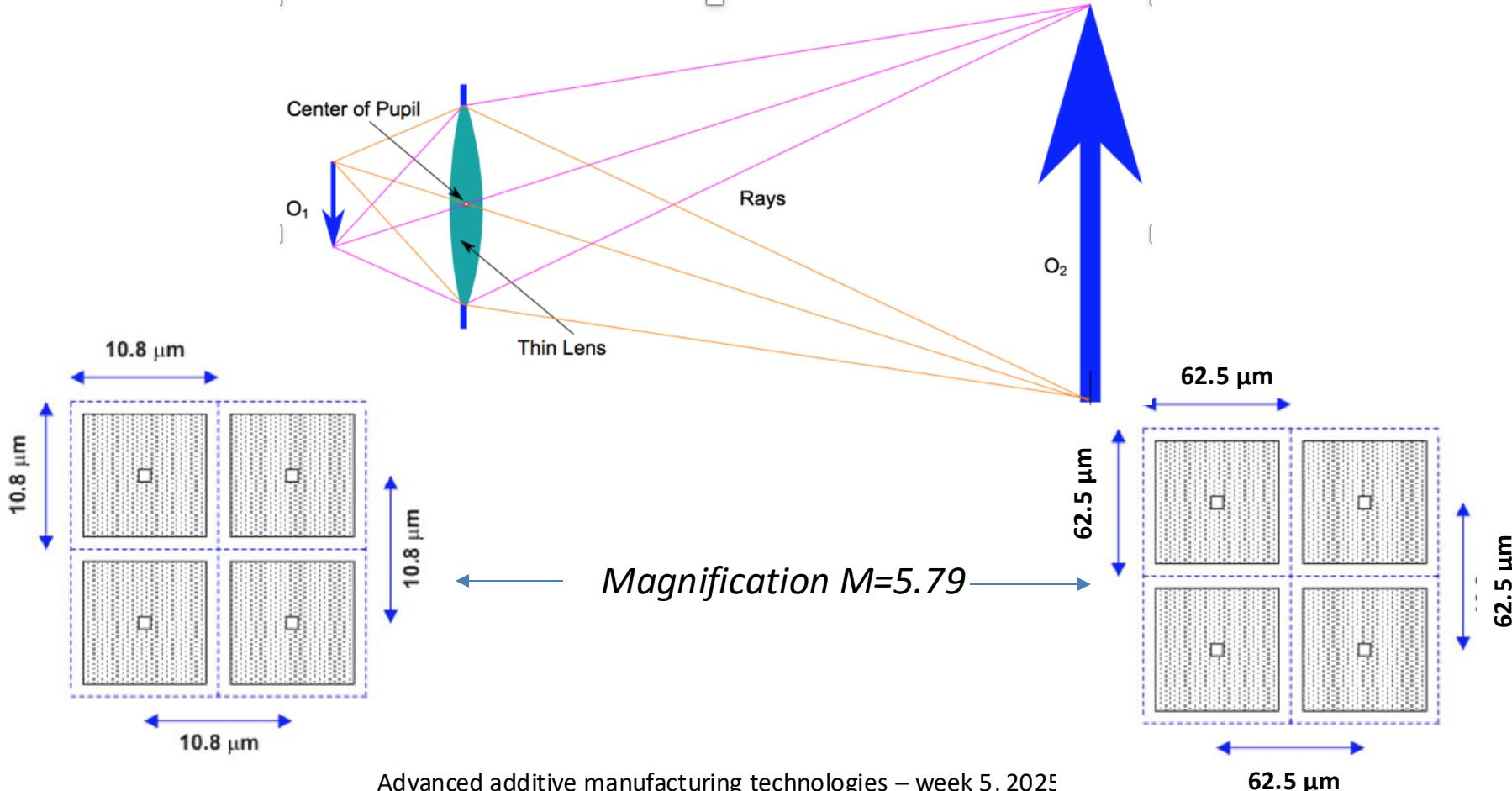




Draw a sketch of how the components are positioned (light source& board, DMD, lens) based on the system below



Geometrical Optics



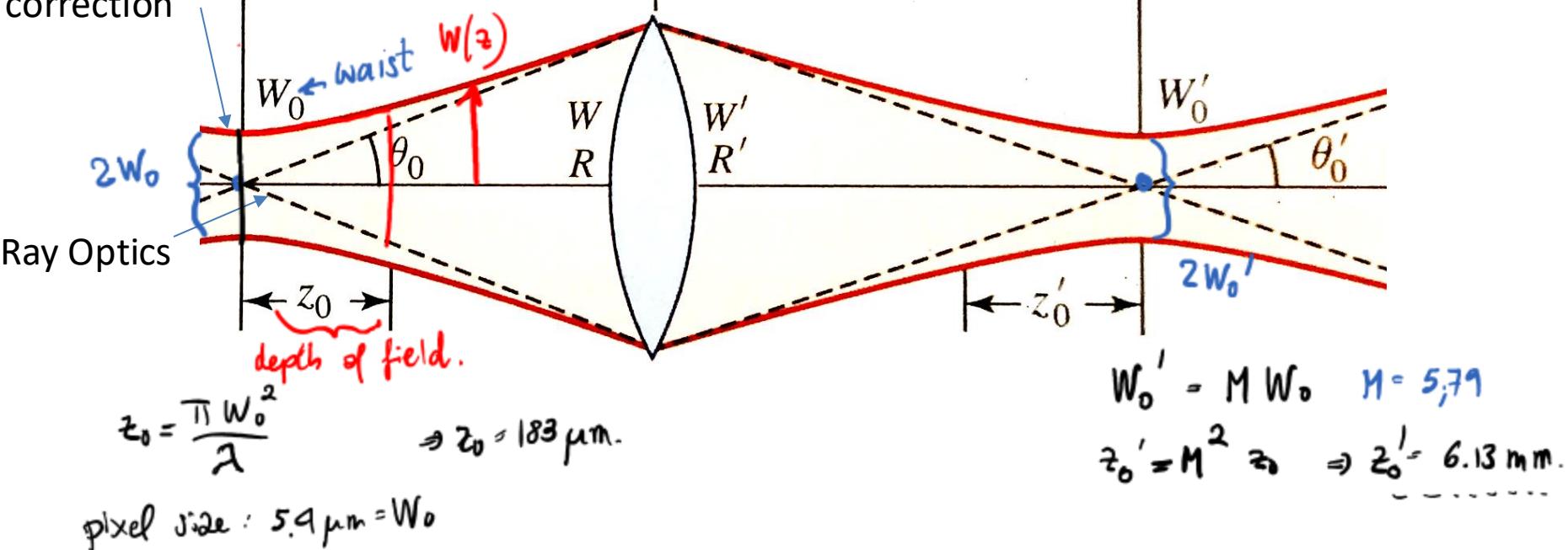
Wave Optics

$$\lambda = 400 \text{ nm.}$$

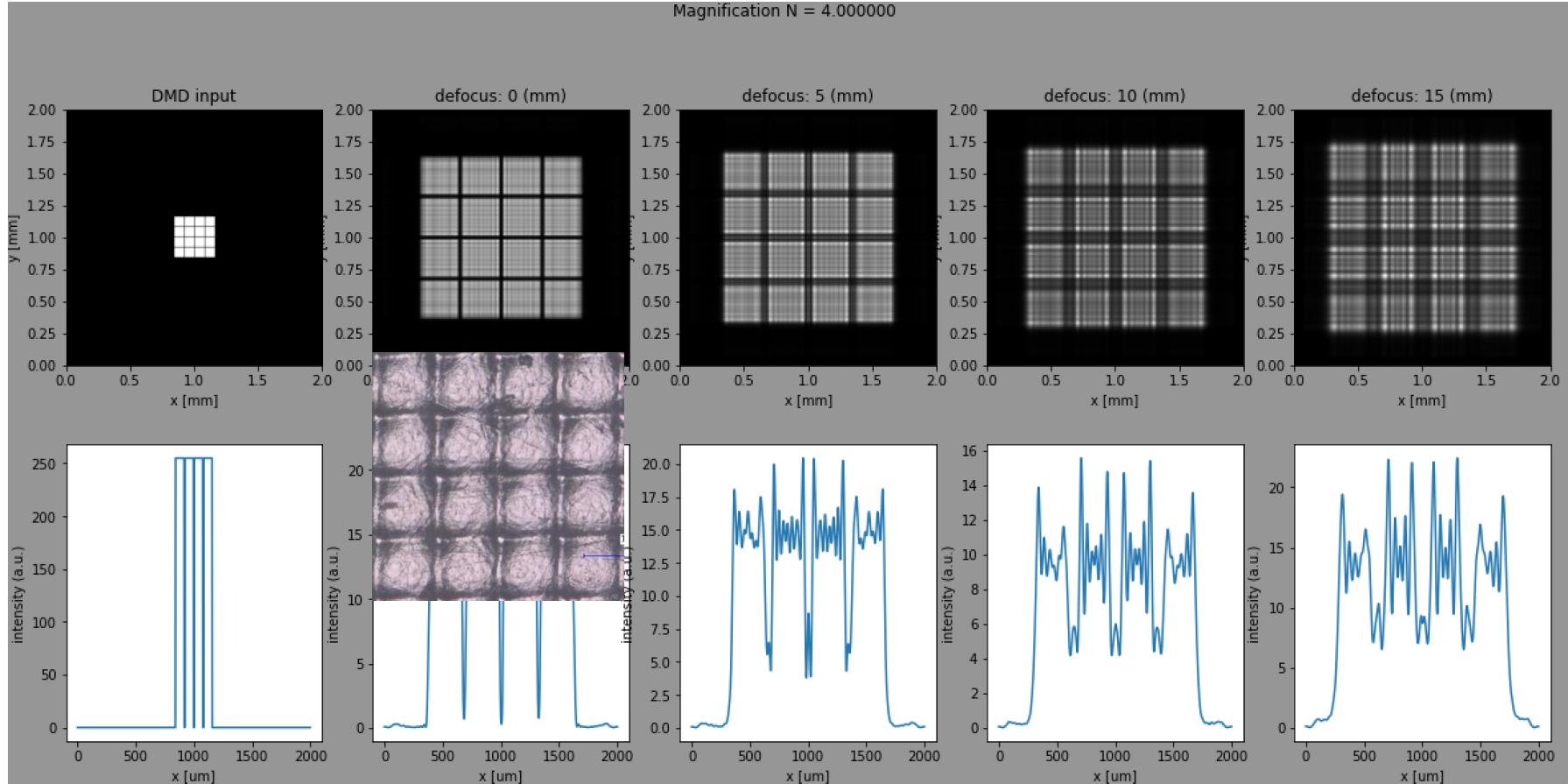
NOT TO SCALE

$$W(z) = W_0 \sqrt{1 + \left(\frac{z}{z_0}\right)^2}, \quad W(z=z_0) = \delta z \cdot W_0$$

Wave optics
correction

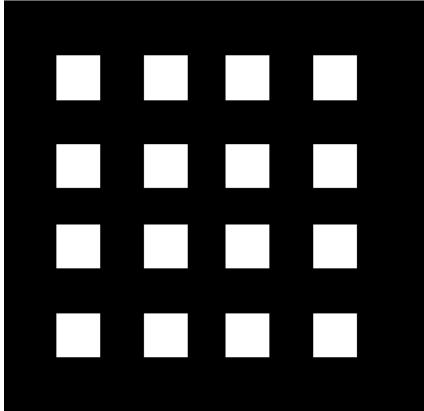


Simulation



Simulation

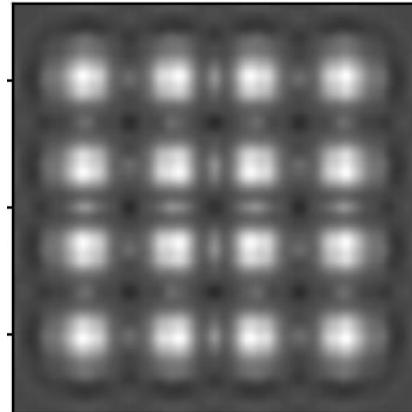
Input



(exercise)

Image plane

Output



Real surface measurement

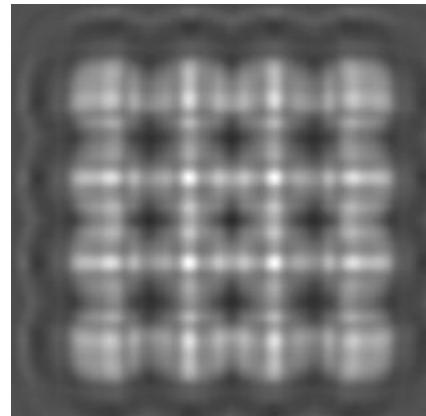
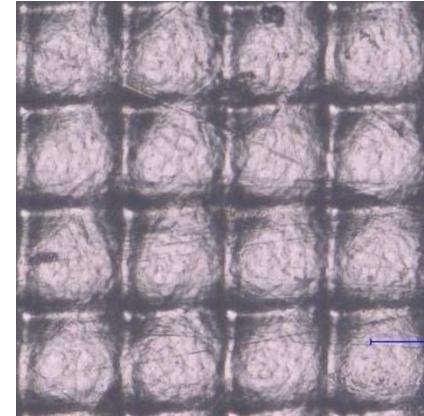


Image plane + 2mm

Example

Design a DLP printer projector for microlithography i.e we are interested in making small but high resolution structures. Assume we want to achieve 10 um spatial resolution with a build volume of 15 x 15 x 15 mm.

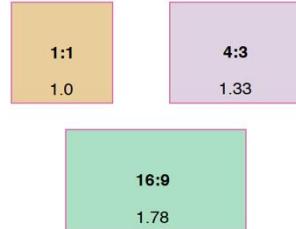


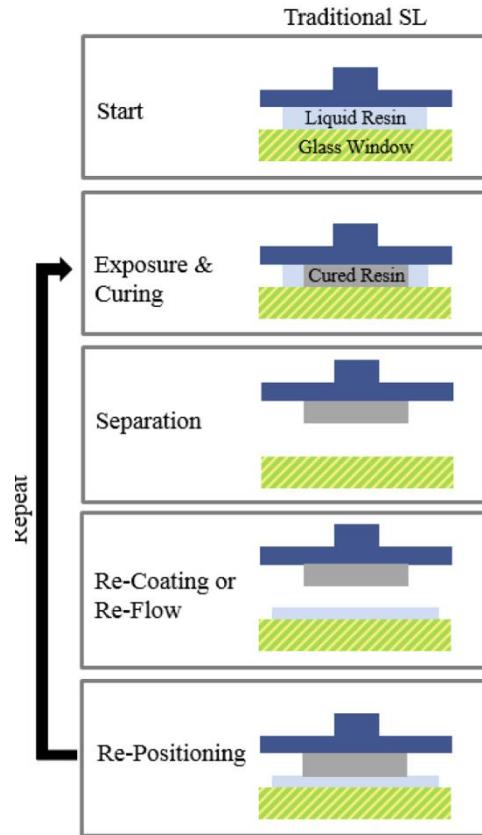
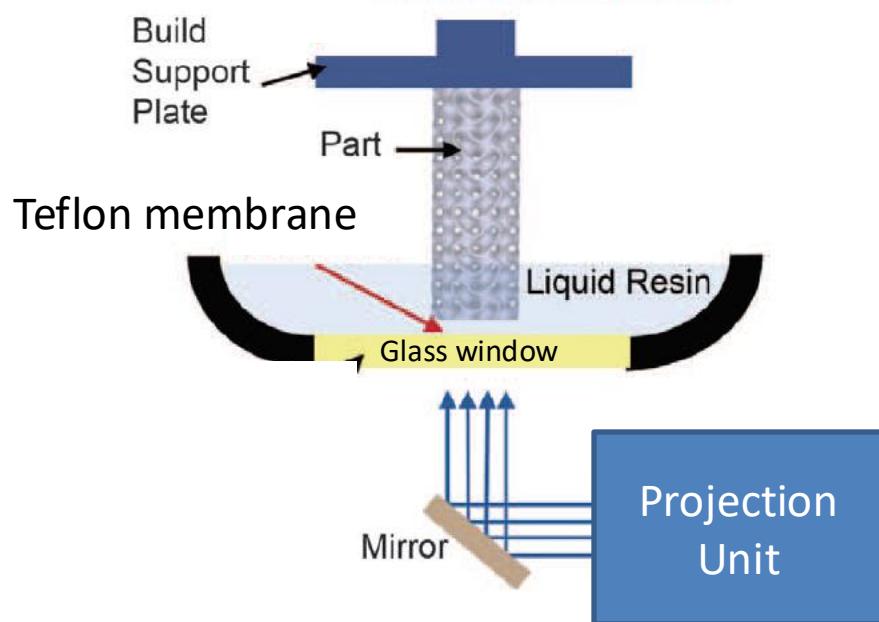
Figure 1. Aspect Ratios

i.e Find the lens, the distance of the DLP chip to the lens , distance of the image plane from the lens (i.e where the resin container is located)



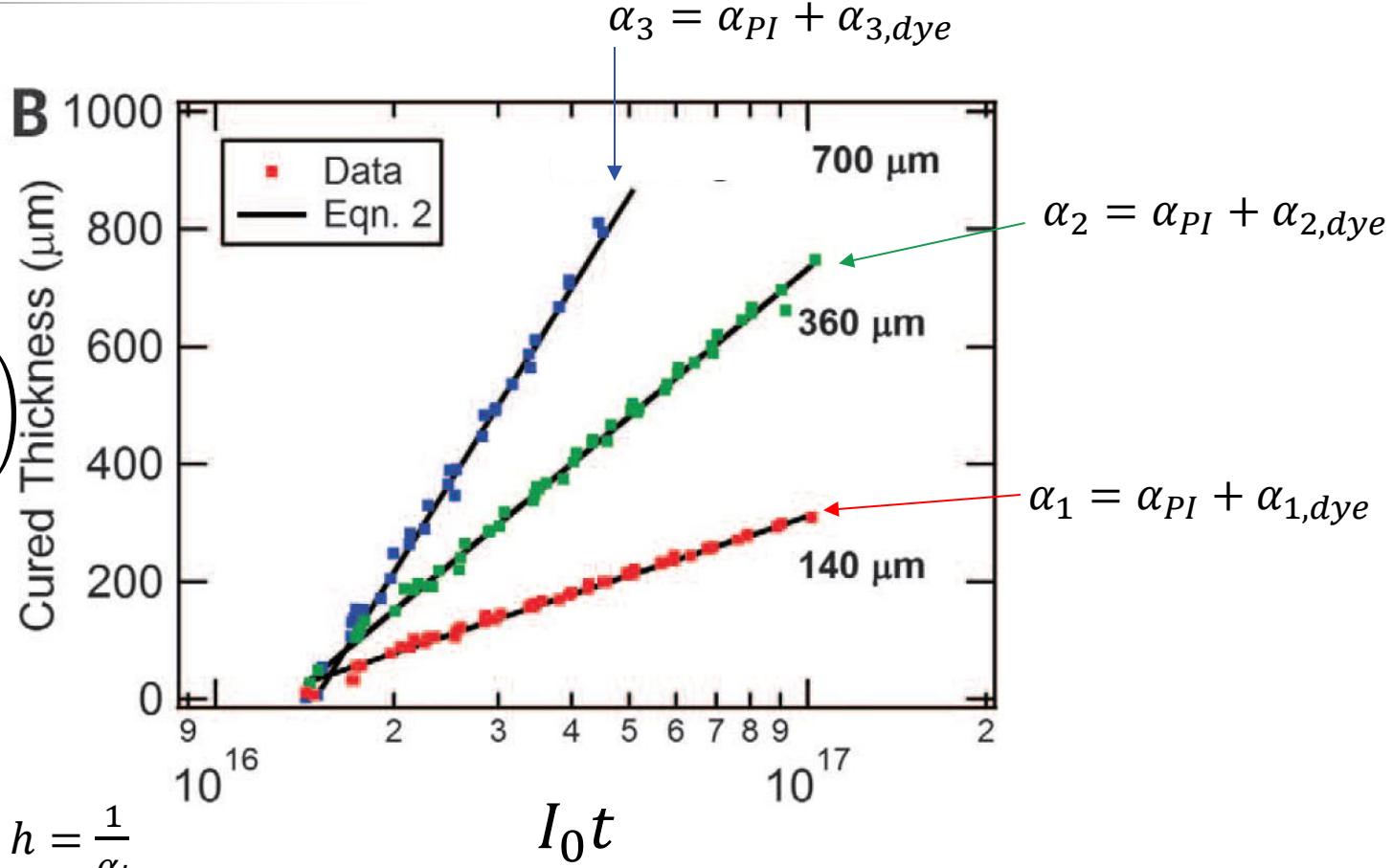
Figure 2. DLP DMDs With Their Aspect Ratios

DLP 3D printing



$$z_{ct} = \frac{1}{\alpha_i} \ln \left(\frac{\alpha_i I_0 t}{D_c} \right)$$

$$\text{Penetration depth } h = \frac{1}{\alpha_i}$$



RESIN PARAMETERS

FH1100 STANDARD RESIN

Appearance	Gray
Density (g/cm ³)	1.14
Viscosity (cps)	350 cps (25°C)
Critical Exposure Ec (mJ/cm ²)	12 mJ/cm ²
Penetration Depth (dp)	0.2 mm

As comparison

Water has a viscosity of 1 cps at 20°C

